

PRODUCTION CONTROL SYSTEM OF SEMICONDUCTOR WAFER

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PURPOSE: To prevent a wafer from being damaged, to prevent dust from attaching to a wafer, to prevent the mixture of lots, and to carry wafers efficiently by storing and processing the process status and stock status semiconductor wafers based on information of a wafer recognizing means installed on a wafer storing means.

CONSTITUTION: A wafer storing means which is constituted of a cassette magazine is not located as a work-in-process stock on a line side of each process K but is collectively stored on a magazine shelf 50a of a stereo stocker 50. When the wafer storing means are stored, a bar code provided on each wafer is read and the specification information and the stored place of each wafer are stored in a host computer. Afterwards, on request from a process K, the magazine shelf 50a wherein the cassette magazine is stored is referred to for searching the requested wafer and the magazine which stores the requested wafer is carried to the process K using an unmanned carrier 51b. By this method, an automatic delivery of wafers is achieved.

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